

UC Berkeley

EE C245 - ME C218 Introduction to MEMS Design Fall 2011

Prof. Clark T.-C. Nguyen

Dept. of Electrical Engineering & Computer Sciences
University of California at Berkeley
Berkeley, CA 94720

Lecture Module 2: Benefits of Scaling

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 1

UC Berkeley

Lecture Outline

- Reading: Senturia, Chapter 1
- Lecture Topics:
 - ↳ Benefits of Miniaturization
 - ↳ Examples
 - ↳ GHz micromechanical resonators
 - ↳ Chip-scale atomic clock
 - ↳ Micro gas chromatograph

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 2

UC Berkeley

Benefits of Size Reduction: MEMS

- Benefits of size reduction clear for IC's in elect. domain
 - ↳ size reduction \Rightarrow speed, low power, complexity, economy
- MEMS: enables a similar concept, but ...
MEMS extends the benefits of size reduction beyond the electrical domain

↓

Performance enhancements for application domains beyond those satisfied by electronics in the same general categories

- Speed \Rightarrow Frequency \uparrow , Thermal Time Const. \downarrow
- Power Consumption \Rightarrow Actuation Energy \downarrow , Heating Power \downarrow
- Complexity \Rightarrow Integration Density \uparrow , Functionality \uparrow
- Economy \Rightarrow Batch Fab. Pot. \uparrow (esp. for packaging)
- Robustness \Rightarrow g-Force Resilience \uparrow

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 3

UC Berkeley

Vibrating RF MEMS

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 4

Basic Concept: Scaling Guitar Strings

Guitar String

Vib. Amplitude vs Freq. (110 Hz)

Vibrating "A" String (110 Hz)

Freq. Equation:

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

Stiffness (k_r) and Mass (m_r) are indicated.

μMechanical Resonator

Metallized Electrode, Anchor, Polysilicon Clamped-Clamped Beam, L_r, W_r, h_r

[Bannon 1996]

Transmission (dB) vs Frequency (MHz)

Performance:
 L_r=40.8μm
 m_r ~ 10⁻¹³ kg
 W_r=8μm, h_r=2μm
 d=1000Å, V_F=5V
 Press.=70mTorr

f_o=8.5MHz
 Q_{vac}=8,000
 Q_{air}~50

Frequency of a Stretched Wire

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 6

Frequency of a Clamped-Clamped Beam

Metallized Electrode, Anchor, Polysilicon Clamped-Clamped Beam, W_r, L_r, h_r

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 7

Frequency of a Clamped-Clamped Beam

EE C245: Introduction to MEMS Design LecM 2 C. Nguyen 8/20/09 8

Basic Concept: Scaling Guitar Strings

Guitar String

Stiffness

Mass

Freq. Equation:

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

μ Mechanical Resonator

[Bannon 1996]

Performance:
 $L_r=40.8\mu\text{m}$
 $m_r \sim 10^{-13}\text{ kg}$
 $W_r=8\mu\text{m}, h_r=2\mu\text{m}$
 $d=1000\text{\AA}, V_P=5\text{V}$
 $\text{Press.}=70\text{mTorr}$

$f_o=8.5\text{MHz}$
 $Q_{\text{vac}}=8,000$
 $Q_{\text{air}} \sim 50$

3CC $3\lambda/4$ Bridged μ Mechanical Filter

Performance:
 $f_o=9\text{MHz}, BW=20\text{kHz}, PBW=0.2\%$
 $I.L.=2.79\text{dB}, \text{Stop. Rej.}=51\text{dB}$
 $20\text{dB S.F.}=1.95, 40\text{dB S.F.}=6.45$

[S.-S. Li, Nguyen, FCS'05]

Design:
 $L_r=40\mu\text{m}$
 $W_r=6.5\mu\text{m}$
 $h_r=2\mu\text{m}$
 $L_c=3.5\mu\text{m}$
 $L_b=1.6\mu\text{m}$
 $V_P=10.47\text{V}$
 $P=5\text{dBm}$
 $R_Q=R_{Qo}=12\text{k}\Omega$

Micromechanical Filter Circuit

1.51-GHz, Q=11,555 Nanocrystalline Diamond Disk μ Mechanical Resonator

- Impedance-mismatched stem for reduced anchor dissipation
- Operated in the 2nd radial-contour mode
- $Q \sim 11,555$ (vacuum); $Q \sim 10,100$ (air)
- **Below:** 20 μm diameter disk

Design/Performance:
 $R=10\mu\text{m}, t=2.2\mu\text{m}, d=800\text{\AA}, V_P=7\text{V}$
 $f_o=1.51\text{ GHz (2}^{\text{nd}}\text{ mode), } Q=11,555$

[Wang, Butler, Nguyen MEMS'04]



